

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of:	)	<b>CONFIRMATION NO.: 5022</b>
	)	
<b>Seishi MURAKAMI, et al.</b>	)	
	)	
U.S. Serial No.: 10/584,642	)	Group Art Unit: 1715
	)	
Filed: June 13, 2007	)	Examiner: Mandy C. Louie

For: **FORMATION OF TITANIUM NITRIDE FILM**

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed September 8, 2010 is due by October 8, 2010.  
The Action required restriction among four patentably distinct inventions.

Applicants hereby elect Group I of claims 1-9, 11-14, and 19-24, drawn to a method of vapor deposition, for examination in this application. Applicants advise that no change in the inventorship of the application will be required by the eventual cancellation of non-elected claims.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,

SMITH, GAMBRELL & RUSSELL, LLP

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